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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of: Mostafazadeh et al.

Attorney Docket No.: NSC1P274/P05649

Application No.: 10/650,325

Examiner: Junghwa M. Im

Filed: August 27, 2003

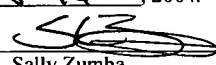
Group: 2811

Title: A SUBSTRATE FOR USE IN  
SEMICONDUCTOR MANUFACTURING AND  
METHOD OF MAKING SAME

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450 on August 16, 2004.

Signed: \_\_\_\_\_

  
Sally Zumba

**RESPONSE TO RESTRICTION REQUIREMENT**

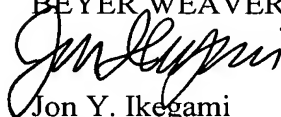
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Restriction Requirement mailed on July 14, 2004, Applicant hereby elects, without traverse, Group 1, claims 1-23, to prosecute in the above-identified patent application.

If any fees are due in connection with the filing of this Response to Restriction Requirement, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. NSC1P297).

Respectfully submitted,  
BEYER WEAVER & THOMAS, LLP



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